

09-06-05

IFW 1765

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT		Docket Number <b>10191/2262</b>	
Application Number <b>10/070,286</b>	Filing Date <b>July 8, 2002</b>	Examiner <b>Anita Karen Alanko</b>	Art Unit <b>1765</b>
Title <b>METHOD FOR PRODUCING A SEMICONDUCTOR COMPONENT AND A SEMICONDUCTOR COMPONENT PRODUCED ACCORDING TO THE METHOD</b>		Applicant(s) <b>Hubert BENZEL et al.</b>	

Address to:  
Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references (cited during prosecution of the corresponding German patent application) to the attention of the Examiner. The references are listed on the attached modified PTO Form No. 1449.

This Supplemental Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(i), which provides that an Information Disclosure Statement that is filed before the grant of a patent but that does not otherwise comply with 37 C.F.R. § 1.97 and § 1.98 will be placed in the file, but not be considered by the Office.

2. To the extent that the reference is considered, the Commissioner is hereby authorized to charge payment of any appropriate fees that may be required to the deposit amount of **Kenyon & Kenyon**, deposit account number **11-0600**. A duplicate of this sheet is enclosed.
3. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed unless otherwise stated.

Dated: 9/1/2005By: Richard L. Mayer

Richard L. Mayer (Reg. No. 22,490)

KENYON &amp; KENYON

One Broadway

New York, N.Y. 10004

(212) 425-7200 (telephone)

(212) 425-5288 (facsimile)

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Express Mail No. EV 33246116 US

NYO1 1037957 v1

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT  
PTO-1449**

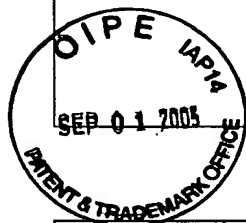
DOCKET NO.  
10191/2262

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10/070,286

APPLICANT  
Hubert BENZEL et al.

FILING DATE  
July 8, 2002

GROUP  
1765



**U. S. PATENT DOCUMENTS**

EXAMINER INITIAL	PATENT/PUBLICATION NUMBER	PATENT/PUBLICATION DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,674,406*	October 7, 1997	Lee			

\* Copy of reference is not enclosed pursuant to Official Gazette Notice dated August 5, 2003.

**FOREIGN PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						Yes	No
	19803013	August 5, 1999	DE			X*	
	4202455	August 19, 1993	DE			X*	
	99/45583	September 10, 1999	WO				

\*\* English language abstract provided.

**OTHER DOCUMENTS**

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Jun-Hwan Sim et al., "Eight-beam piezoresistive accelerometer fabricated by using a selective porous-silicon etching method", pp. 273-8, Sensors and Actuators A66 (1988).
	Walter Lange et al., Sensors and Materials, Vol. 8, no. 6, "Porous Silicon Technology for Thermal Sensors", pp. 327-44 (1986).
	Rosemary L. Smith, "Electrochemical Microfabrication", The Electrochemical Society Proceedings, Proc. Vol. 94-32, Miami Beach Conf., 10-12.10.1994, pp. 281-289 (1995).
	V. Labunov et al., "Heat Treatment Effect on Porous Silicon", Vol. 137, pp. 123-134, Thin Solid Films, 1.3. (1986)

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	